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Method of fabricating an ultra-thin active region for high speed semiconductor devices.

(10) to retard diffusion of a dopant from a center active region (14) into adjacent regions. The center active region is epitaxially formed by selectively increasing and decreasing an introduction of diffusion-suppressing material, preferably germanium, into a semiconductor material, preferably silicon, so that a vertical profile of the content of the diffusion-suppressing material is such that outdiffusion of a dopant is minimized. One embodiment of the tailoring is to increase the concentration of the diffusion-

suppressing material at both of the opposed sides of a base region of a bipolar transistor, thereby providing concentration peaks at the interfaces of the base region with collector (12) and emitter (14) regions. The concentration of germanium in a $\rm Si_{1-x} Ge_x$ layer is such that the value x is within the range 0.08 to 0.35 and optimally within the range 0.15 to 0.31. The dopant, preferably boron, also has a tailored concentration profile to minimize outdiffusion. A thinner, more highly doped active region is thereby achieved.

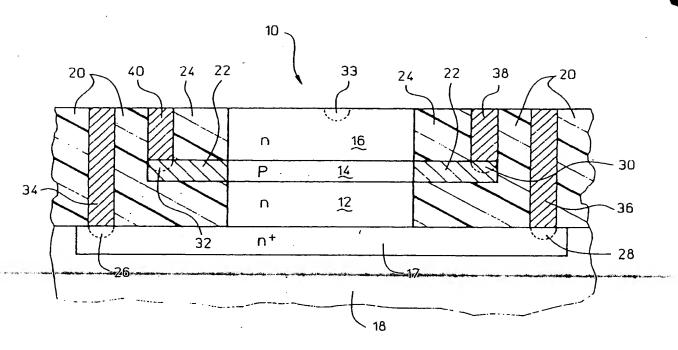


FIG 1



EUROPEAN SEARCH REPORT

Application Number

EP 92 31 1671

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EUROPEAN SEARCH REPORT

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